



PATENT APPLICATION

In re Application of:

Examiner: H. Nguyen

Group Art Unit: 2851

Confirmation No.: 4961

October 8, 2003

MEASUREMENT METHOD, PROJECTION

EXPOSURE APPARATUS MAINTENANCE

MANUFACTURING METHOD, AND

SEMICONDUCTOR MANUFACTURING FACTORY :

Commissioner for Patents

Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

In response to the Official Action dated July 8, 2003, please amend the above-identified

application as follows:

10/09/2003 SSITHIB1 00000041 09866600

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86.00 OP